

DOCKET NO: VSEA 17-03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Alan P. Sheng et al.
Serial No: 10/730,863
Confirmation No: 3529
Filed: December 8, 2003
For: SYSTEM AND METHOD FOR MULTI-WAFER SCANNING IN
ION IMPLANTERS
Examiner: Jack I. Berman .
Art Unit: 2881

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

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Mark Superko

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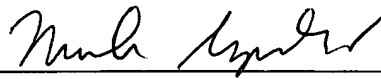
Sir:

Transmitted herewith are the following documents:

- ☒ Amendment
- ☒ Three-month Petition for Extension of Time
- ☒ Return Receipt Postcard

If any additional fees are determined to be required or if there are any overpayments,
Deposit Account 50-0896 may be charged or credited.

Respectfully submitted,
Alan P. Sheng et al., Applicants

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